

*Article*



# **Design of an Intelligent MEMS Safety and Arming Device with a Condition Feedback Function**

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**Abstract:** A safety and arming device with a condition feedback function has been designed in this article to improve the intelligence and safety of ignition devices. The device achieves active control and recoverability by virtue of four groups of bistable mechanisms which consist of two electrothermal actuators to drive a semi-circular barrier and a pawl. According to a specific operation sequence, the barrier is engaged by the pawl at the safety or the arming position. The four groups of bistable mechanisms are connected in parallel, and the device detects the contact resistance generated by the engagement of the barrier and pawl by the voltage division of an external resistor to determine the parallel number of the mechanism and give feedback on the device's condition. The pawl as a safety lock can restrain the in-plane deformation of the barrier in the safety condition to improve the safety function of the device. An igniter (a NiCr bridge foil covered with different thicknesses of Al/CuO films) and boron/potassium nitrate (B/KNO<sup>3</sup> , BPN) are assembled on both sides of the S&A device to verify the safety of the barrier. The test results show that the S&A device with a safety lock can realize the safety and arming functions when the thickness of the  $Al/CuO$  film is set to 80  $\mu$ m and 100 µm.

**Keywords:** safety and arming device; electrothermal actuator; bistable mechanism; condition feedback; **MEMS** 

#### **1. Introduction**

Safety and Arming (S&A) devices are vital to ensuring weapon systems' safety, reliability, and lethality by isolating sensitive igniters from insensitive charges through a removable barrier mechanism to control their energy transfer (allowing standard ignition and preventing accidental ignition). With the demand for miniaturization and intelligence in modern information warfare, MEMS S&A devices have become a focus of research due to their outstanding features such as micromechanics, integrated structure, and intelligent actuation [\[1,](#page-8-0)[2\]](#page-8-1). Existing MEMS S&A devices already have miniaturized structures and different drive principles, but they are still insufficient in terms of intelligence.

The intelligence of S&A devices is reflected in their active control, recoverability, and condition feedback. Actively controlled S&A devices can be armed in arbitrary environments, whereas traditional S&A devices use ammunition-specific environmental information for one-time passive arming. Initially, Charles H. Robinson proposed an inertial-driven micro S&A device for small caliber munition, which is armed by setback load and fabricated by the UV-LIGA process [\[3\]](#page-8-2). Similarly, Seok et al. and Jeong et al. presented two miniature S&A devices armed with setback and centrifugal loads [\[4](#page-8-3)[,5\]](#page-8-4). In addition, Lou et al. designed a micro S&A device for a small caliber projectile that is armed by centrifugal loads [\[6,](#page-8-5)[7\]](#page-8-6). Recently, Lei et al. analyzed the mechanical responses of an inertially driven S&A device under dual-environment inertial loads [\[8\]](#page-8-7). Inertially driven S&A devices are the most reliable, but they are inflexible on a complicated battlefield.



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For novel unmanned combat platforms, such as unmanned aerial vehicles (UAV), the ammunition lacks an inertial environment and does not need to be activated on every  $\Gamma$ mission. Therefore, armed S&A devices must be able to recover to a safe condition to  $\frac{1}{2}$ ensure the safety of the platform's recycling. To ensure the success of each drive, S&A devices urgently need a simple and reliable condition feedback function. Electrically driven<br>Sig-A-derii usus armed by electrical signals, such as electromagnetic and electrothermal S&A devices are armed by electrical signals, such as electromagnetic and electrothermal<br>signals. For example, Hu et al. device al. an electrothermal S&A device that can control signals. For example, Hu et al. designed an electrothermal S&A device that can control barrier's movement with the cooperation of four electrothermal actuators [\[9,](#page-8-8)[10\]](#page-8-9). In andition, Maurer et al. proposed an electromagnetic S&A device in which the barrier  $\alpha$  and  $\beta$ ,  $\beta$ ,  $\beta$  and  $\gamma$  and  $\gamma$  and  $\beta$  and  $\beta$  and  $\beta$  and  $\beta$  and  $\beta$  and  $\gamma$  and  $\$ of paneal by an electromagnetic con [12711] and bain of an presented an electromagnetic coil used in MEMS S&A devices [\[13\]](#page-8-12). All the electrically driven S&A devices can achieve active control and recoverability through bistable mechanisms, but no articles have been active control and recoverability through bistable mechanisms, but no articles have been published on the condition feedback function of MEMS S&A devices. the condition feedback function of MEMS S&A devices. novel unmanned combat platforms, such as unmanned aerial vehicles (UAV), the ammuof nover unitamied compat planomis, such as unifialmed defial venicles (OAV), the

Herein, we propose the design and characterization of an intelligent MEMS S&A Herein, we propose the design and characterization of an intelligent MEMS S&A dedevice with a condition feedback function, which is an improvement of an electrothermal vice with a condition feedback function, which is an improvement of an electrothermal bistable S&A device [\[14](#page-8-13)[–16\]](#page-8-14). This intelligent S&A device has a smaller size (5.8  $\times$  5.8 mm<sup>2</sup>), lower drive voltage (11 V), and higher safety (barrier safety lock) through an optimized lower drive voltage (11 V), and higher safety (barrier safety lock) through an optimized structural layout. The device uses two actuators to control a pawl and a barrier so that structural layout. The device uses two actuators to control a pawl and a barrier so that they can engage or disengage to realize the bistability of the barrier and test the pawl and barrier contact to achieve the feedback function. The S&A device is then assembled in an barrier contact to achieve the feedback function. The S&A device is then assembled in an ignition device to test the safety improvement of the safety lock. ignition device to test the safety improvement of the safety lock.

#### **2. Modeling 2. Modeling**

### *2.1. Structure of the Ignition Device 2.1. Structure of the Ignition Device*

The S&A device is designed as an ignition device by assembling an igniter and an The S&A device is designed as an ignition device by assembling an igniter and an ignition powder on both sides, the structure of which is improved based on the previous ignition powder on both sides, the structure of which is improved based on the previous research, with an overall size of  $\Phi 8 \times 3.4$  mm<sup>3</sup>, as shown in Figure [1.](#page-1-0) The center of the S&A device is a double-layer barrier structure with interfaces at the top (diameter of 500  $\mu$ m) for connecting the ignition powder and at the bottom (diameter of  $1000 \mu m$ ) for connecting the igniter, as shown in Figure [1c](#page-1-0). The igniter is a NiCr bridge foil covered with an Al/CuO energetic film which produces a flame to ignite the ignition powder when stimulated by energetic film which produces a flame to ignite the ignition powder when stimulated by an electric current [\[17](#page-8-15)[–20\]](#page-8-16). Boron/potassium nitrate  $(B/KNO<sub>3</sub>, BPN)$  was selected as the ignition powder and assembled in the powder chamber to avoid crushing. ignition powder and assembled in the powder chamber to avoid crushing.

<span id="page-1-0"></span>

Figure 1. Structure of the ignition device. (a) Key components, (b) section view, and (c) detailed view.

## 2.2. Structure of the S&A Device

The S&A device consists of two layers (top layer and bottom layer) of SOI wafers (50  $\mu$ m device layer, 3  $\mu$ m buried layer, and 400  $\mu$ m handle layer) with an overall size of  $5.8 \times 5.8 \times 0.9$  mm<sup>3</sup>, and each layer has two semicircular barriers driven by bistable mechanism, as shown in Figu[re](#page-2-0) 2a. Two layers of the printed circuit board (PCB) and the S&A device form a sandwich structure to protect the chip's structure. In addition, the electrodes of the two-layer chip are connected to the two PCB layers by gold wire leads and then connected by four pads around the PCB. When the S&A device is in a safe condition, the barrier covers the igniter. If the igniter is accidentally stimulated, the flame energy is blocked and cannot reach the BPN, as shown in Figure [2b](#page-2-0). Otherwise, driven by an arming signal, the S&A device will switch to the armed condition to open the igniter. Flame energy is allowed to pass through the S&A device and ignite the BPN, as shown in Figure [2c](#page-2-0). 2c.

<span id="page-2-0"></span>

Figure 2. Structure of the S&A device. (a) Key components, (b) safety condition, and (c) arming condition. condition.

#### *2.3. Driving Principle of the S&A Device*

*2.3. Driving Principle of the S&A Device*  A V-shape electrothermal actuator is selected as the drive unit for the S&A device; its drive theory has been extensively studied and, thus, is not described in this article. The displacement of the electrothermal actuator is too small to drive the barrier and a soft lever mechanism is used to enlarge the deformation. The S&A device uses four groups of bistable mechanisms to independently and synchronously control the double-layer barrier. Each bistable mechanism consists of two actuators driving a barrier and a pawl. The geometric parameters of t[he](#page-3-0) two actuators and the soft lever are shown in Table 1, and all the parameters are expressed in previous research [\[14\]](#page-8-13). Finite element simulations of the bistable mechanism are performed, and the results are shown in Figure [3a](#page-3-1). When the applied voltage is set to 11 V, the barrier and the pawls can generate a displacement of 358  $\mu$ m and 117  $\mu$ m, which is sufficient for the mechanism.

According to a specific operation sequence, the bistable mechanism can control the the pawl as a safety lock engages with the barrier so that the barrier can open only a minute the barrier's movement; (3) The barrier is opened to the arming position; (4) The pawl is closed to prevent the barrier from returning to the safety position; (5) The barrier is closed to engage with the pawl; and (6) In the armed condition, the barrier is engaged with the pawl in the arming position*,* and the pawl is pressed against the limit block. The driven engagement of the actuator and the pawl as shown in Figure [3b](#page-3-1): (1) In the safety condition, angle, and they are non-contact when no signal enters; (2) The pawl is opened to release

signal is two pulse signals with a phase difference, as shown in Figure [3c](#page-3-1). Following a reverse operation process, the S&A device can recover to the safe condition. Distance of the soft beams (*L*d) 30 30 µm

Angle (*θ*) 3 3 °

<span id="page-3-0"></span>



The condition feedback function of the S&A device is realized on the basis of the The condition feedback function of the S&A device is realized on the basis of the bistable mechanism. The electrothermal actuators can be considered as a series connection bistable mechanism. The electrothermal actuators can be considered as a series connection of two resistors ( $R_1$  and  $R_2$  for the barrier actuator;  $R_3$  and  $R_4$  for the pawl actuator). In the armed condition, the barrier and the pawl are pressed tightly, which creates a contact resistance of *R*5. The circuit of the S&A device can be simplified as shown in Figure 3d. sistance of *R*5. The circuit of the S&A device can be simplified as shown in Figure [3](#page-3-1)d. However, in the safety condition, the barrier and the pawl are separated and insulated from However, in the safety condition, the barrier and the pawl are separated and insulated each other. Therefore, the *R*<sub>5</sub> is infinitely large as an open circuit in the safety condition. Accordingly, the condition of the S&A device can be determined by testing the value of the  $R_5$ .

<span id="page-3-1"></span>

Figure 3. Driving Principle of the S&A device. (a) Simulation results, (b) operation process, (c) driven signal, and (**d**) circuit of feedback function.

## **3. Fabrication 3. Fabrication**

The ignition device is prepared by an assembly of each component, including the S&A device, the igniter, and the BPN, where the S&A device is fabricated from a 4-inch SOI wafer by the etching process [\[14–](#page-8-13)[16\]](#page-8-14), as shown in Figure [4a](#page-4-0), and each individual chip, as shown in Figure [4b](#page-4-0). Two layers of the S&A device and two layers of the PCB are bonded by the S&A device and two layers of the PCB are bonded layer-by-layer with epoxy resin, as shown in Figure 4c. The BPN is press-fitted into the layer-by-layer with epoxy resin, as shown in Figure [4c](#page-4-0). The BPN is press-fitted into the powder chamber at a density of  $1.47 \pm 0.21$  g/cm<sup>3</sup> and placed above the S&A device. The igniter is fabricated on a ceramic substrate by a magnetron sputtering process, and the Al/CuO energetic film is filled by ink droplets [\[15](#page-8-17)[,21\]](#page-8-18). All the independent parts are assembled layer by layer to form an ignition device.

<span id="page-4-0"></span>

Figure 4. Fabrication of the ignition device. (a) Four-inch SOI wafer, (b) the S&A device chip, and (**c**) the ignition device. (**c**) the ignition device.

#### **4. Tests and Discussion 4. Tests and Discussion**

#### *4.1. Test of the Bistable Function 4.1. Test of the Bistable Function*

According to the driving principle, the displacement and response time of the elec-According to the driving principle, the displacement and response time of the electrothermal actuator is directly determined by the applied voltage. The response process trothermal actuator is directly determined by the applied voltage. The response process of the barrier and the pawl are recorded by a high-speed camera (5000 fps) from 11 V to 18 V, as shown in Figure 5. The arming time is the time it takes for the pawls and barriers 18 V, as shown in Figure [5.](#page-5-0) The arming time is the time it takes for the pawls and barriers to reach the arming position (pawl: 100 µm; barrier: 300 µm); the arming time as a function to reach the arming position (pawl: 100 µm; barrier: 300 µm); the arming time as a function of the applied voltage is shown in Figur[e 5](#page-5-0)a. The switch time is the time required for the of the applied voltage is shown in Figure 5a. The switch time is the time required for the S&A device to switch to the arming or safety condition; the switch time as a function of S&A device to switch to the arming or safety condition; the switch time as a function of the the applied voltage is shown in Figure 5b. As the applied voltage increases (11 V to 18 V), applied voltage is shown in Figure [5b](#page-5-0). As the applied voltage increases (11 V to 18 V), the actuator takes less time to reach the armed position (barrier: 16.2 ms to 2.8 ms; pawl: 4.4 ms to 1.2 ms), and the switching time also decreases (armed to safe: 34.6 ms to 19.2 ms; safe to armed: 25.6 ms to 15.2 ms). The S&A device switches the condition through a specific operation sequence; the detailed process from safe to armed with an applied voltage of 14 V is shown in Figure [5c](#page-5-0). The electrothermal actuator can increase the drive voltage to increase the heating power, but the cooling process of the actuator is natural cooling independent  $\mathbb{E}$ of the drive voltage. Therefore, in step 3, the barrier spends 11 ms waiting for the pawl to return to its initial position, taking the longest time of all the steps, so the switching time<br>hardly degrees a feeth marith the small dredtor hardly decreases further with the applied voltage.

#### *4.2. Test of the Feedback Function*

The S&A device consists of four identical bistable mechanisms, each containing a barrier actuator ( $R_1 + R_2$ ) and a pawl actuator ( $R_3 + R_4$ ), with the two actuators generating a contact resistance  $R_5$  in the armed condition. To simplify the control circuit, the four groups of bistable mechanisms are connected in parallel to drive the double-layer barrier synchronously, as shown in Figure [6a](#page-5-1). To realize the drive and feedback function, four switches and a feedback resistor  $R_0$  are used to design the control circuit. The source voltage (*Vs*) is set as 14 V. The driving principle of the circuit is shown in Figure [6b](#page-5-1); switch 1 controls the barrier actuator, while switches 2 and 3 control the pawl actuator. Controlling

<span id="page-5-0"></span>

the three switches to turn on/off in a specific sequence (Figure [3c](#page-3-1)) can switch the S&A device's condition.

Figure 5. Test results of the bistable function. (a) Arming time versus applied voltage, (b) switching time versus applied voltage, and (c) the operation sequence of safe to armed with an applied voltage of  $14$  V.

<span id="page-5-1"></span>

Figure 6. Test results of the feedback function. (a) Equivalent circuit of the S&A device, (b) the driving principle, (c) the feedback principle, (d) the test results for an  $R_0$  of 330  $\Omega$ , 430  $\Omega$ , and 510  $\Omega$ in different parallel numbers of the bistable mechanism, and (e) the voltage difference of the  $V_n$ .

Only when all four bistable mechanisms are operating successfully will the S&A device switch to the safe or armed condition. Failure of any one set of mechanisms will cause the drive to fail. Therefore, the feedback function only needs to give feedback on the number of contact resistances  $R_5$  and does not need to give feedback on which specific  $R_5$  is having problems. The feedback principle is designed as shown in Figure [6c](#page-5-1). Switches 1, 2, and 3 are set to the off state, and switch 4 is set to the on state. The current flows through the resistors  $R_1$ ,  $R_5$ ,  $R_3$ , and  $R_0$  in turn. Since the resistance of  $R_5$  is much larger than  $R_1$  and  $R_3$ , the current is small, and the actuator will not operate. The total resistance inside the S&A device is  $R_d = (R_1 + R_3 + R_5)/n$  (*n* is the parallel number of the bistable mechanism). The  $R_d$  is variable with *n*, while the value of  $R_0$  is fixed. Therefore, the voltage division of  $R_0$  as the feedback voltage  $(V_n)$  can give feedback on the resistance change of  $R_d$ . The larger the voltage difference  $(V_n - V_{n-1})$ , the better the detection.  $V_n - V_{n-1}$  can be expressed as:

$$
\begin{cases}\n k = \frac{R_1 + R_3 + R_5}{R_0} \\
V_n - V_{n-1} = V_s \frac{k}{k^2 + (2n-1)k + n(n-1)} (n \ge 2) \\
(V_n - V_{n-1})_{max} = V_s \frac{1}{2\sqrt{n^2 - n} + 2n - 1} \left( k = \sqrt{n^2 - n} \right)\n\end{cases}
$$
\n(1)

when *n* is 4,  $V_n - V_{n-1}$  reaches the minimum value. To make  $V_4 - V_3$  reach the maximum when *n* is 4,  $V_n - V_{n-1}$  reaches the minimum value. To make  $V_4 - V_3$  reach the maximum value of  $0.0718V_s$  (1.01 V), *k* should be taken as  $2\sqrt{3}$ . The measured value of  $R_1 + R_3 + R_5$ is about 1580  $\Omega$ , so  $R_0$  is taken as 330  $\Omega$ , 430  $\Omega$ , and 510  $\Omega$  for testing. The test results are shown in Figure [6d](#page-5-1), where the  $V_n$  can be seen to increase with the  $R_0$  and  $n$ . The voltage difference  $(V_n - V_{n-1})$  is shown in Figure [6e](#page-5-1). The  $V_4 - V_3$  reaches the maximum value (0.98 V) when the  $R_0$  is taken as 430 Ω. Each drive of the S&A device causes a change in  $R_5$ , which in turn changes  $V_n$ . However, the change in  $V_n$  is less than 0.15 V, which does not affect the detection. In the safety condition, the contact resistance  $R_5$  is not present and the value of the  $V_0$  is 0 V. The number of successfully operating bistable mechanisms can be detected by the feedback voltage.

#### *4.3. Test of the Safety and Arming Functions*

The safety and arming functions of the S&A device are used to prevent the BPN from being ignited by the igniter in the safe condition and to allow the BPN to be ignited in the armed condition. To test the safety capability of the device, the igniter was filled with different thicknesses of Al/CuO films to control the magnitude of the flame energy. The resistance of the igniter is 1 Ω, which can be excited by a 100  $\mu$ F capacitor discharging at a charge voltage of 25 V. The safety and arming function of the double-layer barrier have been verified in a previous study [\[15\]](#page-8-17), showing that it can block the flame energy of an Al/CuO film of 50 µm thickness and maintain the complete structure. However, if the flame energy is further increased, the barrier will deform in-plane and lose its safety function.

Therefore, in this article, the pawl is designed as a safety lock to engage with the barrier at the safety position so that the barrier can only open a square gap of 60  $\mu$ m  $\times$  60  $\mu$ m with the safety lock closed, as shown in Figure [7a](#page-7-0). To verify the improvement of the safety lock, the safety and arming functions were tested through Al/CuO film with an 80  $\mu$ m,  $100 \mu m$ , and  $150 \mu m$  thickness; the test results are shown in Table [2.](#page-7-1) Four groups of tests were carried out for each thickness in the safety test and two groups in the arming test. When the thickness of the Al/CuO film was set to 80  $\mu$ m and 100  $\mu$ m, the flame energy was blocked by the barrier as shown in Figure [7b](#page-7-0), and a rectangular gap of 60  $\mu$ m  $\times$  130  $\mu$ m was formed after the safety test, as shown in Figure [7c](#page-7-0). Although the gap of the barrier was enlarged by the flame energy, the BPN was not ignited in the safety tests of the  $80 \mu m$  and 100 µm thick Al/CuO films, so the safety lock significantly improved the safety function of the barrier. The safety lock can only restrain the in-plane deformation of the barrier, not the out-of-plane deformation. When the thickness of the Al/CuO film was set to 150  $\mu$ m, the barrier broke out of the plane as shown in Figure [7d](#page-7-0), causing the BPN to ignite. In the arming test, all of the flame generated by the igniter could flow through the S&A device and ignite the BPN, as shown in Figure [7e](#page-7-0),f. The S&A device with a safety lock can realize

the safety and arming function when the thickness of the Al/CuO film is set to 80  $\mu$ m and  $100 \mu m$ .

<span id="page-7-1"></span>**Table 2.** The test results of the safety and arming function.

Thickness of Al/CuO Film	<b>Charge Quantity of</b> Al/CuO Film	Ignition Test in <b>Safety Condition</b>	<b>Charge Quantity of</b> Al/CuO Film	Ignition Test in <b>Arming Condition</b>
$80 \mu m$	$0.47 \,\mathrm{mg}$	Safety	$0.42 \text{ mg}$	Ignition
	$0.42$ mg	Safety	$0.41$ mg	Ignition
	$0.43 \text{ mg}$	Safety		
	$0.42 \text{ mg}$	Safety		
$100 \mu m$	$0.52 \text{ mg}$	Safety	$0.50 \text{ mg}$	Ignition
	$0.51 \text{ mg}$	Safety	$0.53 \text{ mg}$	Ignition
	$0.51 \text{ mg}$	Safety		
	$0.54$ mg	Safety		
$150 \mu m$	$0.74 \text{ mg}$	Ignition	$0.74 \text{ mg}$	Ignition
	$0.76$ mg	Ignition	$0.76$ mg	Ignition
	$0.73 \text{ mg}$	Ignition		
	$0.74 \text{ mg}$	Ignition		

<span id="page-7-0"></span>

**Figure 7.** Test results of the safety and arming function. **Figure 7.** Test results of the safety and arming function.

#### **5. Conclusions 5. Conclusions**

In this article, an intelligent MEMS safety and arming device with a condition feedback function was designed. The S&A device has a smaller size (5.8  $\times$  5.8  $\times$  0.9 mm<sup>3</sup>), lower driving voltage (11 V), and higher safety (safety lock) through an optimized structural driving voltage (11 V), and higher safety (safety lock) through an optimized structural layout. When the applied voltage was set to 14 V, the S&A device could switch the condition to armed within 17 ms or to safe within 22 ms. In addition, the device can give feedback on the device's condition by the voltage division of an external resistor of 430  $\Omega$ . The feedback voltage can detect the number of successfully operating bistable mechanisms feedback voltage can detect the number of successfully operating bistable mechanisms with a minimum voltage difference of 0.98 V. In summary, the safety lock can improve the safety function so that the device can realize the safety and arming function when the thickness of Al/CuO film is set to 80 µm and 100 µm. This MEMS S&A device with miniaturized

structure and intelligent actuation is suitable for applications in micro combat platforms such as unmanned aerial vehicles (UAV).

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**Conflicts of Interest:** The authors declare no conflict of interest.

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